

**Amendments to the Specification (other than claims):**

Please change the title to read:

**CERAMIC SUSCEPTOR FOR SEMICONDUCTOR MANUFACTURING  
EQUIPMENT**

Please replace the paragraph beginning at page 6, line 6, with the following rewritten paragraph:

Likewise, a ceramic susceptor 11 depicted in Fig. 2 is in the interior thereof furnished with a resistive heating element 13 and meanwhile with a plasma electrode 15. In particular, similarly to the ceramic susceptor 1 of Fig. 1, a ceramic substrate 12a that on one surface has the resistive heating element 13 is joined to a ceramic substrate 12b with a bonding layer [[4]] 14a, but meanwhile a separate ceramic substrate 12c on which the plasma electrode 15 is provided is joined to the other surface of the ceramic substrate 12a by means of a bonding layer 14b made out of glass or ceramic.

Please replace the pending abstract with the following abstract of the disclosure: